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			U. S	S. PATENT DOCUMENTS		
Examiner Initials*	Cite, No.	U.S. Patent I Number Code ²	Ocument Kind (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
me	AA	6,413,802		Hu et al.	07-02-2002	
1// 4	AB	6,372,559		Crowder et al.	04-16-2002	
iha	AC	6,365,465		Chan et al.	04-02-2002	7
14	AD	6,300,182		Yu	10-09-2001	
K.	AE	5,689,127		Chu et al.	11-18-1997	
60	AF	4,859,623		Busta	08-22-1989	
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			F(DREIGN PAT	TENT DOCUMENTS			-
Examiner	Cite	F	Foreign Patent Document		Name of Patentee or	Date of	Pages, Columns, Lines, Where Relevant	110
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Group Art Unit					
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Attorney Docket Number	SC12885TP				
	Application Number Filing Date First Named Inventor Group Art Unit Examiner Name				

		OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No. 1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	7'
1816	AH	MONFRAY, S. et al; "50nm-Gate All Around (GAA)-Silicon On Nothing (SON)-Devices: A Simple Way to Co-Integration of GAA Transistors Within Bulk MOSFET Process"; 2002 Symposium on VLSI Technology; 2002; pp 108-109; 2002 Symposium on VLSI Technology Digest of Technical Papers	
PAK	Al	MONFRAY, S. et al.; "Highly-Performant 38nm SON (Silicon-On-Nothing) P-MOSFETs with 9nm-thick Channels"; 2002 IEEE international SOI Conference; 10/02; pp 20-22	
ppe	AJ	MONFRAY, S. et al.; "SON (Silicon-On-Nothing) P-MOSFETs with Totally Silicided (CoSi ₂) Polysilicon on 5nm-thick Si Films: The Simplest Way to Integration of Metal Gates on Thin FD Channels"; IEDM; 2002; pp 263-266; IEEE	
Ble	AK	YU, Bin et al; "FinFET Scaling to 10nm Gate Length"; IEDM; 2002; pp 251-254; IEEE	
Par	AL	KEDZIERSKI, Jakub et al.; "High_Performance Symmetric-Gate and CMOS-Compatible V ₁ Asymmetric-Gate FinFET Devices"; IEEE; 2001; 4 pp	
ber	AM	CHOI, Y. et al.; "Sub-20nm CMOS FinFET Technologies"; IEDM; 2001; pp 19.1.1-19.1.4; IEEE	
pr	AN	KIM, K. et al.; "Double-Gate CMOS: Symmetrical-Versus Asymmetrical-Gate Devices"; IEEE Transactions on Electron Devices; February, 2001; pp 294-299; Vol 48, No 2; IEEE	·
Yh	AO	MONFRAY, S. et al.; "First 80nm SON (Silicon-On-Nothing) MOSFETs With Perfect Morphology and High Electrical Performance"; IEDM; 2001; pp 29.7.1-29.7.4; IEEE	
B	AP	HISAMOTO, D. et al.; "FinFET-A Self-Aligned Double-Gate (MOSFET) Scalable to 20nm"; IEEE Transactions of Electron Devices; December 2000; pp 2320-2325; Vol 47, No 12; IEEE	

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Examiner Sulfar Signature	Considered	1	27	
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPI Include copy of this form with next communication to applicant.	P 609. Draw line thro	ugh citat	ion, if not i	in conformance and not considered

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Please type a plus sign (+) inside this box. FORM PTO/SB/08 Complete if Known Substitute for form 1449A/PTO **Application Number** INFORMATION DISCLOSURE Filing Date Marius K. Orlowski First Named Inventor STATEMENT BY APPLICANT Group Art Unit **Examiner Name** (use as many sheets as necessary) Attorney Docket Number SC12885TP 3 Sheet 3 OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city Cite No. Examiner Initials' and/or country where published. JURCZAK, M. et al.: "Silicon-on-Nothing (SON) - an Innovative Process for Advanced AO CMOS"; IEEE Transactions on Electron Devices"; November, 2000; pp 2179-2187; Vol 47, No 11; IEEE FOSSUM, J.G. et al.: "Extraordinarily High Drive Currents in Asymmetrical Double-Gate AR MOSFETs"; Superlattices and Microstructures; 2000; pp 525-530; Vol 28; No 5/6; Academic Press JURCZAK, M. et al.; "SON (Silicon on Nothing) - A New Device Architecture for the ULSI AS Era"; Symposium of VLSI Technology Digest of Technical Papers; 1999; pp 29-30 HUANG, X. et al.; "Sub 50-nm FinFET: PMOS"; IEDM; 1999; pp 3.4.1-3.4.4; IEEE AT HISAMOTO, D. et al.; "A Folded-Channel MOSFET for Deep-sub-tenth Micron Era"; IEDM; AU 1998; pp 1032-1034; IEDM W TANAKA, T. et al.; "Ultrafast Operation of Vn-Adjusted p+ -n+ Double-Gate SOI ĀV MOSFET's"; IEEE Electron Device Letters; October 1994; pp 386-388; Vol 15, No 10; IEEE ΑW International Search Report

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Specification, abstract and drawings for Application No. 10/074,732 Filed February 13.

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